**EAST Search History**

**EAST Search History (Prior Art)**

| Ref # | Hits | Search Query | DBs | Default Operator | Plurals | Time Stamp |
|---|---|---|---|---|---|---|
| L4 | 578053 | $5lithograph$3 ((mask reticle pattern$3) same (expos$5 project$3) same (wafer substrate $5resist)) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2010/12/19 20:37 |
| L5 | 221157 | (liquid water fluid oil) near3 immers$3 | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2010/12/19 20:37 |
| L6 | 15539 | (liquid water oil fluid) with between with (substrate wafer $5resist) with (projection optic$3) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2010/12/19 20:37 |
| L7 | 21397 | L4 and (L5 or L6) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2010/12/19 20:37 |
| L8 | 1742 | (moving move movement moved moves scan$4) with (stage table) with ((chang43 different differ adjust$4) near5 (speed velocity)) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2010/12/19 20:38 |
| L9 | 23111 | (stage table) with ((chang$3 different differ adjust$4) near5 (speed velocity)) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2010/12/19 20:39 |
| L10 | 3394 | (moving move movement moved moves scan$4) with (stage table) with ((chang$3 different differ adjust$4) near5 (speed velocity)) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2010/12/19 20:39 |

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|---|---|---|---|---|---|---|
| L11 | 18313 | (distance direction position displacement) with (base based depend$4) with ((chang$3 different differ adjust$4) near5 (speed velocity)) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2010/12/19 20:40 |
| L13 | 41 | (11 same 9) and 10 and 4 and @ad<="20041227" | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2010/12/19 20:41 |

## EAST Search History (Interference)

| Ref # | Hits | Search Query | DBs | Default Operator | Plurals | Time Stamp |
|---|---|---|---|---|---|---|
| L14 | 391946 | $5lithograph$3 ((mask reticle pattern$3) same (expos$5 project$3) same (wafer substrate $5resist)) | US-PGPUB; USPAT; UPAD | OR | ON | 2010/12/19 20:41 |
| L15 | 14349 | (stage table) with ((chang$3 different differ adjust$4) near5 (speed velocity)) | US-PGPUB; USPAT; UPAD | OR | ON | 2010/12/19 20:42 |
| L16 | 2077 | (moving move movement moved moves scan$4) with (stage table) with ((chang$3 different differ adjust$4) near5 (speed velocity)) | US-PGPUB; USPAT; UPAD | OR | ON | 2010/12/19 20:42 |
| L17 | 12157 | (distance direction position displacement) with (base based depend $4) with ((chang$3 different differ adjust$4) near5 (speed velocity)) | US-PGPUB; USPAT; UPAD | OR | ON | 2010/12/19 20:42 |
| L18 | 4 | (14 and 15 and 16 and 17).clm. | US-PGPUB; USPAT; UPAD | OR | ON | 2010/12/19 20:43 |
| L19 | 2 | (16 and 17 and (liquid fluid water oil)).clm. | US-PGPUB; USPAT; UPAD | OR | ON | 2010/12/19 20:44 |

**12/19/2010 8:44:52 PM**
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